

# 10/748,899

## EAST SEARCH NOTES (cont.)

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Part (I) SEARCH STRATEGY

Part (II) SEARCH RESULTS

Part (II) Results Identified As Follows

- (1) PARTIALLY RELEVANT [potential Y or A] DOCUMENTS
- (2) HIGHLY RELEVANT [potential X, Y or A] DOCUMENTS
- (C) DOCUMENTS CITED BY EXAMINER ON FORM PTO-892
- (3) DOCUMENTS CITED BY APPLICANT ON FORM PTO-1449

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101748899  
(1/2)

	Hits	Search Text	DBs
1	120	((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)	USPAT; US-PGPUB
2	2	((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SILICON SAME ELECTRODES)	EPO; JPO; DERWENT
3	6	(SPACER AND (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (SILICON SAME ELECTRODES)) AND ((TRANSMI\$4 OR TRANSPARENT) SAME (MIRROR\$2 OR REFLECT\$3))) (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (MICRO\$1MIRROR\$1 OR MICROELECTROMECHANICAL OR MEMS)))) AND ((359/223).CCLS.)	USPAT; US-PGPUB
4	1	(SPACER SPACING SPACED) AND (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT)))	EPO; JPO; DERWENT
5	7	HUIBERS-ANDREW.IN. AND SPACER) (HUIBERS-ANDREW.IN. AND SPACER.CLM.) (HUIBERS-ANDREW-\$1.IN. AND SPACER.CLM.	USPAT; US-PGPUB
6	628	(359/223).CCLS.	USPAT; US-PGPUB
7	711	(359/291).CCLS.	USPAT; US-PGPUB
8	245	(359/295).CCLS.	USPAT; US-PGPUB
9	282	(359/298).CCLS.	USPAT; US-PGPUB
10	1372	(359/224,290,318,855).CCLS.	USPAT; US-PGPUB
11	18	((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) and ((359/224,290,318,855).CCLS.)	USPAT; US-PGPUB
12	34	((GAP DISTANCE) SAME SPAC\$3 SAME SUBSTRATE\$1) AND ((359/223).CCLS.)	USPAT; US-PGPUB
13	56	((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (SILICON SAME	USPAT; US-PGPUB
14	133	((GAP DISTANCE) SAME SPAC\$3 SAME SUBSTRATE\$1) AND ((359/291).CCLS.)	USPAT; US-PGPUB
15	49	((GAP DISTANCE) SAME SPAC\$3 SAME SUBSTRATE\$1) AND ((359/295).CCLS.)	USPAT; US-PGPUB
16	20	((GAP DISTANCE) SAME SPAC\$3 SAME SUBSTRATE\$1) AND ((359/298).CCLS.)	USPAT; US-PGPUB
17	32	(((GAP DISTANCE) SAME SPAC\$3 SAME SUBSTRATE\$1) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND ((359/223).CCLS.)	USPAT; US-PGPUB
18	129	(((GAP DISTANCE) SAME SPAC\$3 SAME SUBSTRATE\$1) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND ((359/291).CCLS.)	USPAT; US-PGPUB
19	47	(((GAP DISTANCE) SAME SPAC\$3 SAME SUBSTRATE\$1) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND ((359/295).CCLS.)	USPAT; US-PGPUB
20	19	(((GAP DISTANCE) SAME SPAC\$3 SAME SUBSTRATE\$1) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND ((359/298).CCLS.)	USPAT; US-PGPUB
21	15	(SPACER AND (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (SILICON SAME ELECTRODES)) AND ((TRANSMI\$4 OR TRANSPARENT) SAME (MIRROR\$2 OR REFLECT\$3))) (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (MICRO\$1MIRROR\$1 OR MICROELECTROMECHANICAL OR MEMS)))) AND ((359/291).CCLS.)	USPAT; US-PGPUB

	Hits	Search Text	DBs
22	10	(SPACER AND (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (SILICON SAME ELECTRODES)) AND ((TRANSMI\$4 OR TRANSPARENT) SAME (MIRROR\$2 OR REFLECT\$3))) (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (SILICON SAME ELECTRODES)) AND ((TRANSMI\$4 OR TRANSPARENT) SAME (MIRROR\$2 OR REFLECT\$3))) AND (MICRO\$1MIRROR\$1 OR MICROELECTROMECHANICAL OR MEMS))) AND ((359/295).CCL5.)	USPAT; US-PGPUB
23	48	(((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (SILICON SAME ELECTRODES)) AND ((TRANSMI\$4 OR TRANSPARENT) SAME (MIRROR\$2 OR REFLECT\$3))	USPAT; US-PGPUB
24	8	(SPACER AND (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (SILICON SAME ELECTRODES)) AND ((TRANSMI\$4 OR TRANSPARENT) SAME (MIRROR\$2 OR REFLECT\$3))) (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (MICRO\$1MIRROR\$1 OR MICROELECTROMECHANICAL OR MEMS))) AND ((359/298).CCL5.)	USPAT; US-PGPUB
25	4	((GAP DISTANCE) SAME SPACER) AND (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (SILICON SAME ELECTRODES)) AND ((TRANSMI\$4 OR TRANSPARENT) SAME (MIRROR\$2 OR REFLECT\$3)))	USPAT; US-PGPUB
26	50	(((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (MICRO\$1MIRROR\$1 OR MICROELECTROMECHANICAL OR MEMS)	USPAT; US-PGPUB
27	7	((GAP DISTANCE) SAME SPACER) AND (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))) AND (SUBSTRATE\$1 NEAR3 SILICON)) AND (MICRO\$1MIRROR\$1 OR MICROELECTROMECHANICAL OR MEMS))	USPAT; US-PGPUB
28	92	(((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE)))	EPO; JPO; DERWENT
29	9	(SPACER SPACING SPACED) AND (((((((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE)))	EPO; JPO; DERWENT
30	24	(((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME REFLECT\$3) AND ((MODULATOR NEAR2 (LIGHT OR OPTICAL)) SAME SUBSTRATE\$1)) AND (SUBSTRATE\$1 SAME ((FIRST AND SECOND) OR (TOP AND BOTTOM) OR (UPPER AND LOWER) OR (FRONT AND BACK) OR TWO OR DOUBLE))) AND (SUBSTRATE\$1 NEAR4 (TRANSMI\$4 OR TRANSPARENT))	EPO; JPO; DERWENT

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	1	2	C	3	Document ID ▽	Title	Current OR
1	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6690502 B2	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements	359/291
2	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6538800 B2	Reflective spatial light modulator with deflectable elements formed on a light transmissive substrate	359/291
3	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6456413 B1	Planar type optical scanning apparatus and mounting structure thereof	359/199
4	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6452712 B2	Method of manufacturing spatial light modulator and electronic device employing it	359/291
5	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6396619 B1	Deflectable spatial light modulator having stopping mechanisms	359/291
6	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6356378 B1	Double substrate reflective spatial light modulator	359/291
7	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6271955 B1	Method of manufacturing spatial light modulator and electronic device employing it	359/291
8	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6172797 B1	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements	359/291
9	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6107115 A	Method of manufacturing spatial light modulator and electronic device employing it	438/72
10	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6046840 A	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements	359/291
11	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5999306 A	Method of manufacturing spatial light modulator and electronic device employing it	359/295
12	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5926309 A	Light valve target comprising electrostatically-repelled micro-mirrors	359/293
13	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5835256 A	Reflective spatial light modulator with encapsulated micro-mechanical elements	359/291
14	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040012838 A1	Spatial light modulators with light blocking and absorbing areas	359/291
15	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030054588 A1	Methods for depositing, releasing and packaging micro-electromechanical devices on wafer substrates	438/107
16	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020196524 A1	Deflectable micromirrors with stopping mechanisms	359/291
17	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020176150 A1	Double substrate reflective spatial light modulator with self-limiting micro-mechanical elements	359/291

	1	2	C	3	Document ID ▽	Title	Current OR
18	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020132389 A1	Method for making a micromechanical device by using a sacrificial substrate	438/97
19	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020126364 A1	Interferometric modulation of radiation	359/247
20	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020122239 A1	Reflective spatial light modulator with deflectable elements formed on a light transmissive substrate	359/291
21	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020114053 A1	Tilttable-body apparatus, and method of fabricating the same	359/224
22	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020075555 A1	Interferometric modulation of radiation	359/291
23	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20010055146 A1	Method of manufacturing spatial light modulator and electronic device employing it	359/291
24	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20010040675 A1	Method for forming a micromechanical device	355/77

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